		P1. Switchable diffractive liquid crystal lens	**P2**. Fabrication and characterization of organic transistors	**P3**. Design and fabrication of Fresnel optics for THz frequencies	**P4**. Characterization of AlGaN/GaN nano structures	**P5**. Fabrication and characterization of thin film ferroelectric varactors for applications in microwave microelectronics	**P6**. Fabrication and characterization of low-loss coplanar waveguide lines on for microwave IC applications	**P7**. SIN junction thermometers using e-beam lithography and thermal evaporation in direct-write mode	**P8**. Superconductor-Insulator-Normal Metal (SIN) Tunnel Junction Thermometry (Shadow Evaporation Technology)	**P9**. NbN Nanostrip Phase Switch using e-beam lithography and reactive ion etching	**P10**. Towards supersensitive bolometers and electron coolers based on carbon nanotubes	**P11**. Cold-Electron Bolometer (CEB) made by Shadow Evaporation Technique	**P12**. Microstructure of thermally grown Si-layers	**P13**. Wafer surface cleaning with a new technique	**P14**. Strain-induced modification of the antiferromagnetic order in epitaxial thin films	**P15**. Effect on post-metallization anneal and hydrogenation on interface states in SiC MOS devices	**P16**. Double-side flip-chip fabrication of intrinsic Josephson junctions
1	840904 830509		2		3						1						
2	821024 810330		1		3								2	4			
3	820312 810701						3			2	1						
4	810527 830619	2	1								3						
5	820127 830810							1	3	2							
6	830904 831124 800616		3							2	1						
7	770113 830601	3			1								2				
8	820801 771224					3				2	1						
9	840322 811024 840430		2							3	1						
10	810726															1	
11	771111 830314									1							